



Laser Micro/Nano Fabrication

Guest Editor:

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Deadline for manuscript
submissions:

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Message from the Guest Editor

Dear Colleagues,

I invite you to submit to this Special Issue, which seeks research and review articles on laser micro/nano fabrication techniques. These include but are not limited to (1) new laser-based approaches to fabricate micro/nano structures, (2) subtractive methods, precision laser ablation and cutting, (3) additive methods and laser-induced deposition, (4) laser bonding, welding, and forming of components; (5) novel software, CAD, and nanometer precision hardware for direct laser writing, and (6) potential research and industrial applications in optical, electronic, and biological fields. Laser micro/nano fabrication is rapidly becoming a preferred manufacturing method due to its inherent high precision, mask-less nature, and rapid processing speed. This Special Issue aims to feature the latest developments in various applications of laser micromachining.

Dr. Thomas C. Hutchens

Guest Editor





Editor-in-Chief

Message from the Editor-in-Chief

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